

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): SONG, Yeong Su

Group Art Unit: To Be Assigned

Serial No.: 10/583,976

Examiner: To Be Assigned

Filed: June 22, 2006

For: METHOD FOR SETTING PLASMA CHAMBER HAVING AN ADAPTIVE PLASMA SOURCE, PLASMA ETCHING USING THE SAME AND MANUFACTURING METHOD FOR ADAPTIVE PLASMA SOURCE

TRANSMITTAL OF DECLARATION PURSUANT TO 37 C.F.R. §1.63

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Transmitted herewith is a declaration pursuant to 37 C.F.R. §1.63 for the above-identified application.

The surcharge, pursuant to 37 C.F.R. §1.16(e), for filing a declaration on a date later than the filing date of the application is as follows:

- ☐ Filing by other than a small entity (\$130)
- ☒ **Filing by a small entity (\$65)**
- ☐ A check in the amount of \$_____ to cover the surcharge fee is enclosed.
- ☒ **Charge surcharge fee to Deposit Account No. 13-4500, Order No. 4913-0001.**
- ☒ **The Commissioner is hereby authorized to charge any additional fees which may be required for filing this paper, or credit any overpayment to Deposit Account No. 13-4500, Order No. 4913-0001.**

Respectfully submitted,
MORGAN & FINNEGAN, L.L.P.

Dated: September 19, 2006

By: 

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